

INTERNATIONAL STANDARD

Synthetic quartz crystal – Specifications and guidelines for use



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Synthetic quartz crystal – Specifications and guidelines for use

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CONTENTS

FOREWORD.....	6
INTRODUCTION.....	8
1 Scope.....	9
2 Normative references.....	9
3 Terms and definitions	9
4 Specification for synthetic quartz crystal.....	13
4.1 Standard values	13
4.1.1 Shape of synthetic quartz for optical applications.....	13
4.1.2 Orientation of the seed.....	13
4.1.3 Inclusion density	13
4.1.4 Striae in synthetic quartz for optical applications.....	14
4.1.5 Infrared quality indications of $\alpha_3 500$ and $\alpha_3 585$ for piezoelectric applications	14
4.1.6 Grade classification by α value and Schlieren method for optical applications	15
4.1.7 Frequency-temperature characteristics of synthetic quartz for piezoelectric applications	15
4.1.8 Etch channel density ρ	15
4.1.9 Internal transmittance for optical applications	16
4.2 Requirements and measuring methods	17
4.2.1 Orientation.....	17
4.2.2 Handedness.....	18
4.2.3 Synthetic quartz crystal dimensions	18
4.2.4 Seed dimensions	19
4.2.5 Imperfections	19
4.2.6 Evaluation of infrared quality by α measurement.....	22
4.2.7 Frequency versus temperature characteristics for piezoelectric applications	24
4.2.8 Striae in synthetic quartz for optical applications.....	25
4.2.9 Growth band in synthetic quartz for optical applications	25
4.2.10 Etch channel density.....	26
4.2.11 Internal transmittance for optical applications	27
4.3 Marking.....	27
4.3.1 General	27
4.3.2 Shipping requirements	28
5 Specification for lumbered synthetic quartz crystal	28
5.1 Standard values	28
5.1.1 Tolerance of dimensions	28
5.1.2 Reference surface flatness.....	29
5.1.3 Angular tolerance of reference surface	29
5.1.4 Centrality of the seed	30
5.2 Requirements and measuring methods	31
5.2.1 As-grown quartz bars used for lumbered quartz bars	31
5.2.2 Dimensions of lumbered synthetic quartz crystal.....	31
5.2.3 Identification on reference surface.....	31
5.2.4 Measurement of reference surface flatness.....	31

5.2.5	Measurement of reference surface angle tolerance	31
5.2.6	Centrality of the seed	31
5.3	Delivery conditions	32
5.3.1	General	32
5.3.2	Marking	32
5.3.3	Packing	32
5.3.4	Making batch	32
6	Inspection rule for synthetic quartz crystal and lumbered synthetic quartz crystal	32
6.1	Inspection rule for as-grown synthetic quartz crystal	32
6.1.1	Inspection	32
6.1.2	Lot-by-lot test	32
6.2	Inspection rule for lumbered synthetic quartz crystal	33
6.2.1	General	33
6.2.2	Lot-by-lot test	34
7	Guidelines for the use of synthetic quartz crystal for piezoelectric applications	34
7.1	General	34
7.1.1	Overview	34
7.1.2	Synthetic quartz crystal	34
7.2	Shape and size of synthetic quartz crystal	35
7.2.1	Crystal axis and face designation	35
7.2.2	Seed	36
7.2.3	Shapes and dimensions	36
7.2.4	Growth zones	37
7.3	Standard method for evaluating the quality of synthetic quartz crystal	37
7.4	Other methods for checking the quality of synthetic quartz crystal	38
7.4.1	General	38
7.4.2	Visual inspection	38
7.4.3	Infrared radiation absorption method	38
7.4.4	Miscellaneous	39
7.5	α grade for piezoelectric quartz	40
7.6	Optional grading (only as ordered), in inclusions, etch channels, Al content	40
7.6.1	Inclusions	40
7.6.2	Etch channels	40
7.6.3	Al content	40
7.6.4	Swept quartz	41
7.7	Ordering	42
Annex A (informative)	Frequently used sampling procedures	43
A.1	Complete volume counting	43
A.2	Commodity Y-bar sampling – Method 1	43
A.3	Commodity Y-bar sampling – Method 2	43
A.4	Use of comparative standards for 100 % crystal inspection	44
Annex B (informative)	Numerical example	45
Annex C (informative)	Example of reference sample selection	46
Annex D (informative)	Explanations of point callipers	47
Annex E (informative)	Infrared absorbance α value compensation	48
E.1	General	48
E.2	Sample preparation, equipment set-up and measuring procedure	48
E.2.1	General	48

E.2.2	Sample preparation.....	48
E.2.3	Equipment set-up.....	48
E.2.4	Measurement procedure.....	49
E.3	Procedure to establish correction terms.....	49
E.4	Calculation of compensated (corrected) absorbance values.....	51
Annex F (informative)	Differences of the orthogonal axial system for quartz between IEC standard and IEEE standard.....	52
Annex G (informative)	α value measurement consistency between dispersive infrared spectrometer and fourier transform infrared spectrometer.....	54
G.1	General.....	54
G.2	Experiment.....	54
G.3	Experimental result.....	55
Bibliography	58
Figure 1	– Quartz crystal axis and cut direction.....	17
Figure 2	– Idealized sections of a synthetic quartz crystal grown on a Z-cut seed.....	19
Figure 3	– Typical example of cutting wafers of AT-cut plate, minor rhombohedral-cut plate, X-cut plate, Y-cut plate and Z-cut plate.....	21
Figure 4	– Frequency-temperature characteristics deviation rate of the test specimen.....	25
Figure 5	– Typical schlieren system setup.....	25
Figure 6	– Lumbered synthetic quartz crystal outline and dimensions along X-, Y- and Z-axes.....	29
Figure 7	– Angular deviation for reference surface.....	30
Figure 8	– Centrality of the seed with respect to the dimension along the Z- or Z'-axis.....	31
Figure 9	– Quartz crystal axis and face designation.....	36
Figure 10	– Synthetic quartz crystal grown on a Z-cut seed of small X-dimensions.....	37
Figure 11	– Example of a relation between the α value and the Q value at wave number $3\,500\text{ cm}^{-1}$	39
Figure D.1	– Point callipers.....	47
Figure D.2	– Digital point callipers.....	47
Figure E.1	– Schematic of measurement set-up.....	49
Figure E.2	– Graph relationship between averaged α and measured α at two wave numbers of $\alpha_{3\,500}$ and $\alpha_{3\,585}$	50
Figure F.1	– Left- and right-handed quartz crystals.....	53
Figure G.1	– Relationship of α between measuring value and reference value.....	57
Table 1	– Inclusion density grades for piezoelectric applications.....	14
Table 2	– Inclusion density grades for optical applications.....	14
Table 3	– Infrared absorbance coefficient grades for piezoelectric applications.....	14
Table 4	– Infrared absorbance coefficient grades and Schlieren method for optical applications.....	15
Table 5	– Etch channel density grades for piezoelectric applications.....	16
Table 6	– Test conditions and requirements for the lot-by-lot test for group A.....	33
Table 7	– Test conditions and requirements for the lot-by-lot test for group B.....	33
Table 8	– Test conditions and requirements for the lot-by-lot test.....	34
Table B.1	– Commodity bar sampling, method 1.....	45

Table B.2 – Commodity bar sampling45
Table E.1 – Example of calibration data at α_3 58550
Table E.2 – Example of calibration data at α_3 50050

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INTERNATIONAL ELECTROTECHNICAL COMMISSION

**SYNTHETIC QUARTZ CRYSTAL –
SPECIFICATIONS AND GUIDELINES FOR USE**

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International Standard IEC 60758 has been prepared by IEC technical committee 49: Piezoelectric, dielectric and electrostatic devices and associated materials for frequency control, selection and detection.

This fifth edition cancels and replaces the fourth edition, published in 2008. This edition constitutes a technical revision.

This edition includes the following significant technical changes with respect to the previous edition:

- order rearrangement and review of terms and definitions;
- abolition as a standard of the infrared absorbance coefficient α_3 410;
- addition of the α value measurement explanation by FT-IR equipment in annex;
- addition of the synthetic quartz crystal standards for optical applications.

The text of this standard is based on the following documents:

FDIS	Report on voting
49/1185/FDIS	49/1190/RVD

Full information on the voting for the approval of this standard can be found in the report on voting indicated in the above table.

This publication has been drafted in accordance with the ISO/IEC Directives, Part 2.

The committee has decided that the contents of this publication will remain unchanged until the stability date indicated on the IEC website under "<http://webstore.iec.ch>" in the data related to the specific publication. At this date, the publication will be

- reconfirmed,
- withdrawn,
- replaced by a revised edition, or
- amended.

A bilingual version of this publication may be issued at a later date.

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INTRODUCTION

The reason for adding synthetic quartz crystal for optical application to this International Standard is as follows.

Quartz crystal produced for optical applications is produced by many of the same suppliers manufacturing quartz for electronic applications. The equipment and methods to produce optical quartz are similar to those used in the production of electronic quartz. Also, with a few exceptions the characterization methods of electronic and optical material are similar. Therefore, IEC 60758 serves as the proper basis for including addenda related to quartz crystal for optical applications.

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SYNTHETIC QUARTZ CRYSTAL – SPECIFICATIONS AND GUIDELINES FOR USE

1 Scope

This International Standard applies to synthetic quartz single crystals intended for manufacturing piezoelectric elements for frequency control, selection and optical applications.

2 Normative references

The following documents, in whole or in part, are normatively referenced in this document and are indispensable for its application. For dated references, only the edition cited applies. For undated references, the latest edition of the referenced document (including any amendments) applies.

IEC 60068-1:2013, *Environmental testing – Part 1: General and guidance*

IEC 60122-1:2002, *Quartz crystal units of assessed quality – Part 1: Generic specification*

IEC 60410, *Sampling plans and procedures for inspection by attributes*

IEC 61994 (all parts), *Piezoelectric and dielectric devices for frequency control and selection – Glossary*

3 Terms and definitions

For the purposes of this document, the terms and definitions given in IEC 61994 and the following apply.

3.1

hydrothermal crystal growth

crystal growth in the presence of water, elevated temperatures and pressures by a crystal growth process believed to proceed geologically within the earth's crust

Note 1 to entry: The industrial synthetic quartz growth processes utilize alkaline water solutions confined within autoclaves at supercritical temperatures (330 °C to 400 °C) and pressures (700 to 2 000 atmospheres).

Note 2 to entry: The autoclave is divided into two chambers: the dissolving chamber, containing raw quartz chips at the higher temperature; the growing chamber, containing cut seeds at the lower temperature (see 7.1.2).

3.2

synthetic quartz crystal

single crystal of α quartz grown by the hydrothermal method

Note 1 to entry: Cultured quartz has the same meaning as synthetic quartz crystal.

3.3

as-grown synthetic quartz crystal

state of synthetic quartz crystal prior to grinding or cutting

3.4

as-grown Y-bar

crystals which are grown by using long stick seed in the Y-direction